

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

December 21, 2007

In re the application of:

S. Panda et al.

Docket No. 175P012

Filed: 11/25/2003

Art Unit: 1765

Serial No.: 10/721,657

Examiner: Lan Vinh

For: Method of Processing Wafers With
Resonant Heating

Confirmation No. 7420

**REQUEST FOR CONTINUED EXAMINATION (RCE)
AND SUBMISSION IN ACCORDANCE WITH 37 C.F.R. § 1.117**

Mail Stop RCE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the final Office Action dated September 26, 2007, and identified as Paper No. 20070921, please consider the following Request for Continued Examination (RCE) and submission under 37 C.F.R. § 1.117.

Amendments to the Claims begins of page 2 of this paper.

Remarks/Arguments begin on page 4 of this paper.